

Hisashi Kino

List of Publications by Year in descending order

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#	ARTICLE	IF	CITATIONS
1	Reconfigured-Wafer-to-Wafer 3-D Integration Using Parallel Self-Assembly of Chips With Cu-SnAg Microbumps and a Nonconductive Film. IEEE Transactions on Electron Devices, 2014, 61, 533-539.	3.0	41
2	Remarkable Suppression of Local Stress in 3D IC by Manganese Nitride-Based Filler with Large Negative CTE. , 2017, , .		19
3	Oxide-Oxide Thermocompression Direct Bonding Technologies with Capillary Self-Assembly for Multichip-to-Wafer Heterogeneous 3D System Integration. Micromachines, 2016, 7, 184.	2.9	17
4	Investigation of Local Bending Stress Effect on Complementary Metal-Oxide Semiconductor Characteristics in Thinned Si Chip for Chip-to-Wafer Three-Dimensional Integration. Japanese Journal of Applied Physics, 2013, 52, 04CB11.	1.5	16
5	Development of Eccentric Spin Coating of Polymer Liner for Low-Temperature TSV Technology With Ultra-Fine Diameter. IEEE Electron Device Letters, 2019, 40, 95-98.	3.9	14
6	Self-Assembly and Electrostatic Carrier Technology for Via-Last TSV Formation Using Transfer Stacking-Based Chip-to-Wafer 3-D Integration. IEEE Transactions on Electron Devices, 2017, 64, 5065-5072.	3.0	11
7	Development of highly-reliable microbump bonding technology using self-assembly of NCF-covered KGDs and multi-layer 3D stacking challenges. , 2015, , .		10
8	Impact of Chip-Edge Structures on Alignment Accuracies of Self-Assembled Dies for Microelectronic System Integration. Journal of Microelectromechanical Systems, 2016, 25, 91-100.	2.5	9
9	Deteriorated Device Characteristics in 3D-LSI Caused by Distorted Silicon Lattice. IEEE Transactions on Electron Devices, 2014, 61, 540-547.	3.0	8
10	Vertical-cavity surface-emitting laser chip bonding by surface-tension-driven self-assembly for optoelectronic heterogeneous integration. Japanese Journal of Applied Physics, 2015, 54, 030206.	1.5	8
11	Effect of local stress induced by thermal expansion of underfill in three-dimensional stacked IC. Japanese Journal of Applied Physics, 2016, 55, 04EC03.	1.5	8
12	Experimental evaluation of stimulus current generator with Laplacian edge-enhancement for 3-D stacked retinal prosthesis chip. , 2017, , .		6
13	Development of integrated photoplethysmographic recording circuit for trans-nail pulse-wave monitoring system. Japanese Journal of Applied Physics, 2018, 57, 04FM11.	1.5	6
14	Tunnel field-effect transistor charge-trapping memory with steep subthreshold slope and large memory window. Japanese Journal of Applied Physics, 2018, 57, 04FE07.	1.5	6
15	Charge-Trap-Free Polymer-Liner Through-Silicon Vias for Reliability Improvement of 3D ICs. , 2018, , .		6
16	Self-Assembly Technologies for FlexTrateâ„¢. , 2018, , .		6
17	Mechanical and Electrical Characterization of FOWLP-Based Flexible Hybrid Electronics (FHE) for Biomedical Sensor Application. , 2019, , .		6
18	Investigation of TSV Liner Interface With Multiwell Structured TSV to Suppress Noise Propagation in Mixed-Signal 3D-IC. IEEE Journal of the Electron Devices Society, 2019, 7, 1225-1231.	2.1	6

#	ARTICLE	IF	CITATIONS
19	Study of Al-doped ZnO Transparent Stimulus Electrode for Fully Implantable Retinal Prosthesis with Three-dimensionally Stacked Retinal Prosthesis Chip. Sensors and Materials, 2018, , 225.	0.5	6
20	Minimization of Keep-Out-Zone (KOZ) in 3D IC by local bending stress suppression with low temperature curing adhesive. , 2014, , .		5
21	3-D Sidewall Interconnect Formation Climbing Over Self-Assembled KGDs for Large-Area Heterogeneous Integration. IEEE Transactions on Electron Devices, 2017, 64, 2912-2918.	3.0	5
22	PPG and SpO ₂ Recording Circuit with Ambient Light Cancellation for Trans-Nail Pulse-Wave Monitoring System. , 2019, , .		5
23	High-Thermoresistant Temporary Bonding Technology for Multichip-to-Wafer 3-D Integration With Via-Last TSVs. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2019, 9, 181-188.	2.5	5
24	RDL-first Flexible FOWLP Technology with Dielets Embedded in Hydrogel. , 2020, , .		5
25	Significant Die-Shift Reduction and $\frac{1}{4}$ LED Integration Based on Die-First Fan-Out Wafer-Level Packaging for Flexible Hybrid Electronics. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2020, 10, 1419-1422.	2.5	5
26	On-wafer thermomechanical characterization of a thin film polyimide formed by vapor deposition polymerization for through-silicon via applications: Comparison to plasma-enhanced chemical vapor deposition SiO ₂ . Journal of Polymer Science, 2020, 58, 2248-2258.	3.8	5
27	Room-Temperature Cu Direct Bonding Technology Enabling 3D Integration with Micro-LEDs. , 2022, , .		5
28	MOSFET Nonvolatile Memory with High-Density Cobalt-Nanodots Floating Gate and HfO_2 High-k Blocking Dielectric. IEEE Nanotechnology Magazine, 2011, 10, 528-531.	2.0	4
29	Fabrication and In vivo Evaluation of Poly(3,4-ethylenedioxythiophene) Stimulus Electrodes for Fully Implantable Retinal Prosthesis. Japanese Journal of Applied Physics, 2013, 52, 04CL03.	1.5	4
30	Design and evaluation of area-efficient and wide-range impedance analysis circuit for multichannel high-quality brain signal recording system. Japanese Journal of Applied Physics, 2016, 55, 04EM12.	1.5	4
31	Minimized hysteresis and low parasitic capacitance TSV with PBO (polybenzoxazole) liner to achieve ultra-high-speed data transmission. , 2017, , .		4
32	The Effect of Mechanical Stress on Cell Characteristics in MONOS Structures. IEEE Transactions on Electron Devices, 2018, 65, 4313-4319.	3.0	4
33	Integration of Damage-less Probe Cards Using Nano-TSV Technology for Microbumped Wafer Testing. , 2021, , .		4
34	Continuous Peripheral Blood Pressure Measurement with ECG and PPG Signals at Fingertips. , 2018, , .		3
35	Multichip thinning technology with temporary bonding for multichip-to-wafer 3D integration. Japanese Journal of Applied Physics, 2020, 59, SBBA04.	1.5	3
36	Generation of STDP With Non-Volatile Tunnel-FET Memory for Large-Scale and Low-Power Spiking Neural Networks. IEEE Journal of the Electron Devices Society, 2020, 8, 1266-1271.	2.1	3

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37	High-thermal-stability resistor formed from manganese nitride compound that exhibits the saturation state of the mean free path. Applied Physics Express, 2021, 14, 091003.	2.4	3
38	Study of Insertion Characteristics of Si Neural Probe with Sharpened Tip for Minimally Invasive Insertion to Brain. Japanese Journal of Applied Physics, 2013, 52, 04CL04.	1.5	2
39	Consideration of microbump layout for reduction of local bending stress due to CTE Mismatch in 3D IC. , 2015, , .		2
40	Impact of deep-via plasma etching process on transistor performance in 3D-IC with via-last backside TSV. , 2015, , .		2
41	Process Integration for FlexTrate TM . , 2018, , .		2
42	The Effect of Tungsten Volume on Residual Stress and Cell Characteristics in MONOS. IEEE Journal of the Electron Devices Society, 2019, 7, 382-387.	2.1	2
43	Characterization of Low-Height Solder Microbump Bonding for Fine-Pitch Inter-Chip Connection in 3DICs. , 2019, , .		2
44	Development of 3D-IC Embedded Flexible Hybrid System. , 2019, , .		2
45	Symmetric and asymmetric spike-timing-dependent plasticity function realized in a tunnel-field-effect-transistor-based charge-trapping memory. Japanese Journal of Applied Physics, 2020, 59, SGGB12.	1.5	2
46	Low-temperature multichip-to-wafer 3D integration based on via-last TSV with OER-TEOS-CVD and microbump bonding without solder extrusion. , 2020, , .		2
47	7-1/4m-thick NCF technology with low-height solder microbump bonding for 3D integration. , 2020, , .		2
48	Wafer-Level Flexible 3D Corrugated Interconnect Formation for Scalable In-Mold Electronics with Embedded Chiplets. , 2021, , .		2
49	Development of Manganese Nitride Resistor with Near-Zero Temperature-Coefficient of Resistance to Achieve High-Thermal-Stability ICs. , 2021, , .		2
50	Novel local stress evaluation method in 3D IC using DRAM cell array with planar mOS capacitors. , 2015, , .		1
51	Evaluation of in-plane local stress distribution in stacked IC chip using dynamic random access memory cell array for highly reliable three-dimensional IC. Japanese Journal of Applied Physics, 2016, 55, 04EC07.	1.5	1
52	Wide-range and precise tissue impedance analysis circuit with ultralow current source using gate-induced drain-leakage current. , 2016, , .		1
53	Drastic reduction of keep-out-zone in 3D-IC by local stress suppression with negative-CTE filler. , 2016, , .		1
54	Evaluation of insertion characteristics of less invasive Si optoneural probe with embedded optical fiber. Japanese Journal of Applied Physics, 2017, 56, 04CM08.	1.5	1

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55	Noise Propagation through TSV in Mixed-Signal 3D-IC and Investigation of Liner Interface with Multi-Well Structured TSV. , 2019, , .		1
56	Investigation of the Impact of External Stress on Memory Characteristics by Modifying the Backside of Substrate. IEEE Transactions on Electron Devices, 2019, 66, 1741-1746.	3.0	1
57	Investigation of the Underfill with Negative-Thermal-Expansion Material to Suppress Mechanical Stress in 3D Integration System. , 2019, , .		1
58	Development of Non-Volatile Tunnel-FET Memory as a Synaptic Device for Low-Power Spiking Neural Networks. , 2020, , .		1
59	Design and Evaluation of Electronic-Microsaccade with Balanced Stimulation for Artificial Vision System. , 2021, , .		1
60	HIGH ENDURANCE NON-VOLATILE SEMICONDUCTOR MEMORY FOR FULLY IMPLANTABLE RETINAL PROSTHESIS. , 2012, , .		0
61	Highly sensitive pressure sensor with silicon-on-nothing (SON) MOSFET for sensor integrated heterogeneous system. , 2016, , .		0
62	Ultrawide range square wave impedance analysis circuit with ultra-slow ring-oscillator using gate-induced drain-leakage current. , 2017, , .		0
63	Design and evaluation of wide-range and low-power analog front-end enabling body-implanted devices to monitor charge injection properties. Japanese Journal of Applied Physics, 2017, 56, 04CM05.	1.5	0
64	Development of Si neural probe with piezoresistive force sensor for minimally invasive and precise monitoring of insertion forces. Japanese Journal of Applied Physics, 2017, 56, 04CM04.	1.5	0
65	Mechanical Characterization of FOWLPBased Flexible Hybrid Electronics (FHE) for Biomedical Sensor Application. , 2019, , .		0
66	Impacts of Deposition Temperature and Annealing Condition on Ozone-Ethylene Radical Generation-TEOS-CVD SiO ₂ for Low-Temperature TSV Liner Formation. , 2019, , .		0
67	Multichip thinning technology with temporary bonding for multichip-to-wafer 3D integration. , 2019, , .		0
68	Development of a CDS Circuit for 3-D Stacked Neural Network Chip using CMOS Analog Signal Processing. , 2019, , .		0